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TITLE: METHOD OF DETECTING WIRING DEFECT  
USING ELECTRON BEAM  
TESTER AND ELECTRON BEAM TESTER  
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ABSTRACT:

PROBLEM TO BE SOLVED: To provide a method of easily detecting wiring defect by observing a wide area using an electron beam tester.

SOLUTION: The method of detecting wiring defect comprises a floating step of floating a wiring 2, an irradiation step of irradiating the wiring with an electron beam under the condition where the wiring is electrified to a negative potential, a supplying step of supplying a positive voltage

from one external  
terminal 3 of the wiring, and an observing step of  
observing a potential  
contrast image of the wiring 2. The breaking point 2p  
between the bright  
section and the dark section of the wiring 2 on the  
potential contrast image is  
detected.

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